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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Rajesh Khamankar, et al.

Docket No: TI-33223

Serial No: 10/702,234

Conf. No: 7943

Examiner: Nathan W. Ha

Art Unit: 2814

Filed: 11/06/2003

For: RELIABLE HIGH VOLTAGE GATE DIELECTRIC LAYERS USING A DUAL NITRIDATION PROCESS

AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(a)

I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 3-18-05.


Ann Trent

Dear Sir:

Responsive to the Office Action mailed December 20, 2004, in connection with the above identified application, Applicants respectfully submit the following amendments and remarks.